

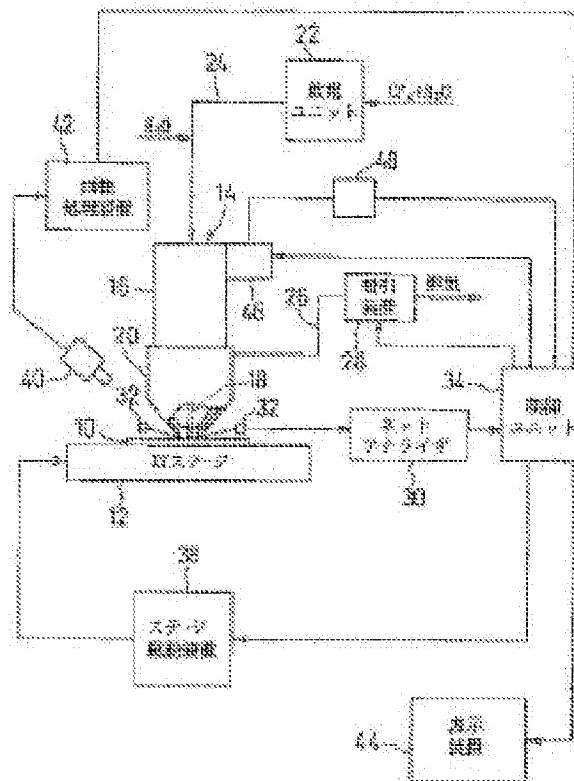
Family list1 application(s) for: **JP11308065 (A)****METHOD AND DEVICE FOR ADJUSTING FREQUENCY OF
CRYSTAL RESONATOR****Inventor:** MIYAJIMA HIROO ; ASUKE SHINTARO (+1)**EC:****Publication info:** JP11308065 (A) - 1999-11-05
JP3726488 (B2) - 2005-12-14**Applicant:** SEIKO EPSON CORP**IPC:** H01L21/302; H03H3/04; H01L21/02; (+3)**Priority Date:** 1998-04-23Data supplied from the **espacenet** database — Worldwide

METHOD AND DEVICE FOR ADJUSTING FREQUENCY OF CRYSTAL RESONATOR

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Applicant(s):	SEIKO EPSON CORP +	
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Application number:	JP19980113942 19980423	
Priority number(s):	JP19980113942 19980423	

Abstract of JP 11308065 (A)

PROBLEM TO BE SOLVED: To easily adjust frequency in atmospheric pressure. **SOLUTION:** In a crystal wafer 10, a 1st resonator chip is arranged at a working position by an XY stage 12. An image processor 42 inputs to a control unit 34 that the chip is set to the working position from an image-pickup image of a positioning camera 40. A processing unit 14 makes a jetting nozzle 18 spray reaction gas from a discharging unit 22 to the wafer 10, an absorption nozzle 20 absorbs jetted reaction gas and locally etches the crystal wafer.; The unit 34 controls the position of the unit 14 via a drive mechanism 46, based on a detection signal of a position sensor 48, makes the unit 14 move and etch crystal, stops the etching of the wafer 10 when an oscillation frequency detected by a net analyzer 30 becomes a reference value, feeds the stage 12 by a prescribed pitch and sets the next chip to the working position.



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